

**VERSION WITH MARKINGS TO SHOW CHANGES MADE**

**In the Claims:**

Claim 1 has been amended as follows:

--1 (Amended). A piezoelectric device comprising a first element of pure porous crystalline silicon, a second element being attached to, or integrally formed with, said first element, and at least one electrode being in electrical contact solely with said first element of said first and second elements, such that subjecting said first element to an electric potential via said at least one electrode results in a strain induced by said first element on said second element. --

Claim 29 has been amended as follows:

--29 (Amended). A method of inducing a strain by a first element of pure porous crystalline silicon on a second element, the method comprising the steps of attaching to, or integrally forming with, the first element, the second element, and having at least one electrode being in electrical contact solely with the first element of the first and second elements, such that subjecting the first element to an electric potential via said at least one electrode results in a strain induced by the first element on the second element. --